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Fabrication of polymer hierarchical structures by two-step temperature-directed capillary lithography

H. E. Jeong, S. H. Lee, J. K. Kim and K. Y. Suh* (Mechanical and Aerospace Eng. Dept., SNU)

ABSTRACT

A simple method for fabricating micro/nanoscale hierarchical structures is presented using a two-step temperature-directed capillary molding technique. This lithographic method involves a sequential application of molding process in which a uniform polymer-coated surface is molded with a patterned mold by means of capillary force above the glass transition temperature of the polymer. Using this approach, multiscale hierarchical structures for biomimetic functional surfaces can be fabricated with precise control over geometrical parameters and the wettability of a solid surface can be designed in a controllable manner.

Key Words : Micro/nanscale hierarchical structures (/), Capillary lithography (), Contact angle (), Wettability (/)

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vapor-induced phase separation, crystallization of polyethylene

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/ 가

가 , wettability

가

wettability

2.

2.1.2

가 PDMS

(120 °, 1 hr),

가 PUA

2 가
(120 °, 5 min).

PS, PMMA

PDMS

(~ 1.8 MPa)

100 nm

가

가

PUA 가

PUA

가 50 μm

PDMS

(tensile modulus of ~ 40 MPa) 가

, PUA

가

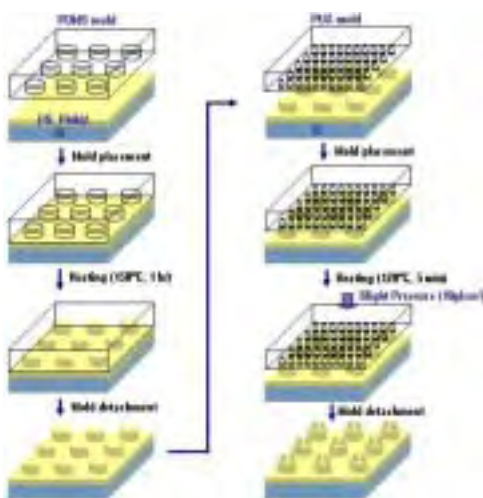


Fig. 1 A schematic diagram of the two-step temperature-directed capillary molding process

2.2 SEM

(SEM, XL30FEG)

(Phoenix 150, SEO Co., Korea).

3.

(nanolines, nanopillars)

700

70

(2)

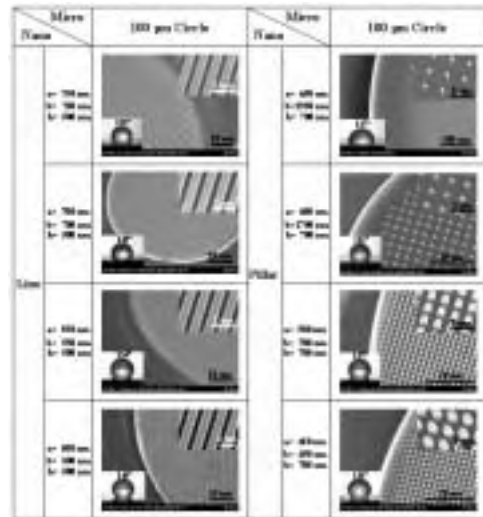


Fig. 2 SEM images of various nanolines and nanopillars with different sizes on the same pre-formed microstructure (100 μm cylinders)

2 가 가

가
Cassie state

Wenzel state

가 ('Cassie-Wenzel state')

, 가

Cassie state 가

('Cassie-Cassie state')

, 'Cassie-Wenzel state'

가

Cassie-Baxter Wenzel

$$\cos \theta_2 = r \cos \theta_1 = r[f(1 + \cos \theta) - 1] \quad (1)$$

r roughness factor () , f , θ

3 가 2 가 가

8.1%

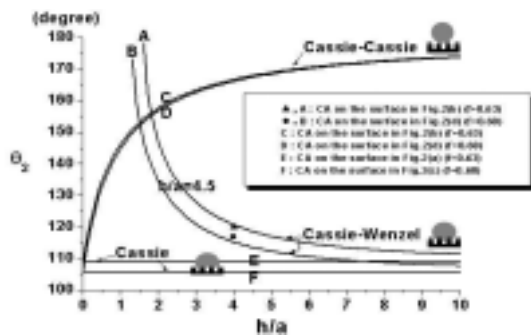


Fig. 3 Comparison of the measured contact angles with the theoretical predictions

wettability

가

30 μm ,

50 μm , spacing 40 μm

PMMA ($\theta = 66^\circ$)

SEM

가

160 $^\circ$

가

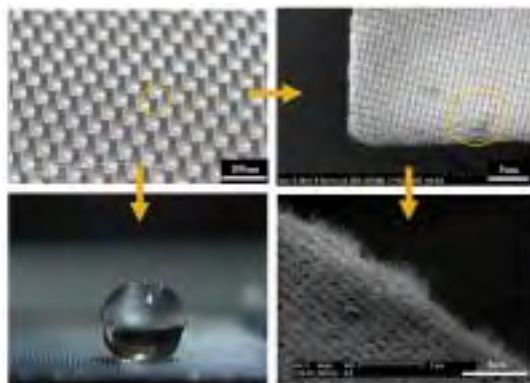


Fig. 4 SEM images of a super-hydrophobic surface consisting of a combination of micro/nanoscale structures along with a image of a water droplet

4.

2

/

. 70 nm

700 nm

nanoline

nanopillar

가

wettability

wettability

가

wettability

Micro Thermal System

Research Center

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